

<b>Session Title:</b>	<b>[Tu1E] Dimensional Metrology III</b>
<b>Session Date:</b>	<b>August 6 (Tue.), 2024</b>
<b>Session Time:</b>	<b>11:00-12:30</b>
<b>Session Room:</b>	<b>Room E (114)</b>
<b>Session Chairs</b>	<b>TBA</b>

**[Tu1E-1] [Invited] 11:00-11:30**

**Double-sided Interferometer for SI-traceable Thickness Measurement**

Akiko Hirai and Youichi Bitou (Nat'l Metrology Inst. of Japan, Japan)

**[Tu1E-2] 11:30-11:45**

**Application for Wafer Measurement using Multi-channel Laser Ranging based on Dual-comb Time-of-flight with High-efficiency Cross-correlation via Semiconductor Optical Amplifier**

Jaeyoung Jang, Hyeokin Kang, Hyunsu Kim, Seung-Woo Kim, and Young-Jin Kim (KAIST, Korea)

**[Tu1E-3] 11:45-12:00**

**Measurement of Temporal Phase of Weak Optical Pulses in a Noisy Environment**

Jerzy Szuniewicz (Univ. of Warsaw, Poland), Steven Sagona-Stophel, Sarah Thomas, Ian Walmsley (Imperial College London, UK), and Michał Karpiński (Univ. of Warsaw, Poland)

**[Tu1E-4] 12:00-12:15**

**Phase Noise Measurement with Delay Interferometer During Fast Polarization Fluctuation**

Shiro Ryu (Meiji Univ., Japan)

**[Tu1E-5] 12:15-12:30**

**Precise Enhancement for Optical Delay Measurement**

Haoxuan Zhang, Weimeng Wang, Song Yu, Bin Luo, and Tianwei Jiang (Beijing Univ. of Posts and Telecommunications, China)